

MRS Co-sponsors Meetings on Ion Beams and Semiconductor Based Heterostructures

Conference on Semiconductor-Based Heterostructures

The 1986 TMS Northeast Regional Conference will deal with semiconductor-based heterostructures such as GaAs epitaxially deposited on Si to create an electro-optic device, or multilayer conductive films for VLSI. The conference, to be held May 1 and 2, 1986, at AT&T Bell Laboratories, Murray Hill, NJ, is co-sponsored by the Materials Research Society.

Highlight topics will include silicon on insulators, Ge on Si, epitaxial silicides, amorphous superlattices, compound semiconductors on silicon, compound semiconductor metallization and passivation, and the processing techniques involved in preparing these heterostructures. Other issues to be discussed will be multilevel metallization schemes for VLSI, strained-layer superlattices, nanocomposite materials, interfacial growth, pseudomorphic growth, ohmic contact to semiconductors, and phase transformations in thin film structures.

Contact the conference chairman, Martin L. Green, AT&T Bell Laboratories, Murray Hill, NJ 07974; telephone (201) 582-3000.

Conference on Low Energy Ion Beams

MRS has announced its co-sponsorship of the Conference on Low Energy Ion Beams to be held April 7-10, 1986, at the University of Sussex, Brighton, UK. The conference chairman is Prof. William A. Grant of the University of Salford, UK., and the organizing committee is drawn from members of the Atomic Collisions in Solids Group of the Institute of Physics, London.

Papers are invited in the following areas: ion sources; excitation, ionization, and charge transfer; ion optics and beam transport; high current and large area beams; accelerators, ion implantation; ion-assisted deposition; sputter profiling; microbeams; low-energy ion beams for surface analysis; and ion beam and plasma etching.

Invited speakers include: G. Dearnaley (Harwell), J. Van der Berg (UMIST) D. Briggs (ICI), R. G. Forbes (University of Surrey), D. G. Armour (University of Salford), P. C. Zalm (Philips), J.J. Cuomo (IBM), and J. Ishikawa (Kyoto).

Contact Prof. William A. Grant, Department of Electronic and Electrical Engin-

earing, University of Salford, Salford M5 4WT, U.K. of The Meetings Office, Institute of Physics, 47 Belgrade Square, London SW1X 8QX, UK.

MRS members are entitled to special registration rates.

FMS Sponsors Electronic Materials Workshop

The Federation of Materials Societies (FMS) is sponsoring a workshop on "Electronic Materials: A Key to U.S. Competitiveness" in Washington, DC, February 25-27, 1986. For this workshop, electronic materials are defined as materials of current and future importance in the development and production of electronic components and devices. The materials include (but are not limited to) semiconductors, dielectrics, magnetic, piezoelectric, opto-electronic materials, and optical fibers. The materials may be in the single crystal, polycrystalline, or amorphous state. Also of interest are materials used in packaging electronic components and devices.

The workshop will generate a position paper on the following issues:

- Why are electronics a key to U.S. competitiveness?
- What is the present position of U.S. electronic materials technology?
- What can we do in the U.S. to maintain (or regain) a competitive position in electronic materials technology?

Contact Betsy Houston, Federation of Materials Societies, 1901 L. Street, NW, Washington, DC 20036.

Role of Interfaces is Topic of Ceramic Microstructures '86

An international conference on "Ceramic Microstructures '86: Role of Interfaces" will be held on the Berkeley campus of the University of California, July 28-31, 1986. This conference is the third in a 10-year interval series that started in 1966. It is also the 22nd in a series of University Conferences on Ceramic Sciences.

The opening session will introduce the role of interfaces and review the current status. Other introductory talks will overview ceramic microstructures, electric properties and microstructures, and mechanical properties and microstructures. Subsequent sessions will present papers on characterization of microstructures, microstructure production, and the effects of interfaces on electrical properties and on mechanical properties.

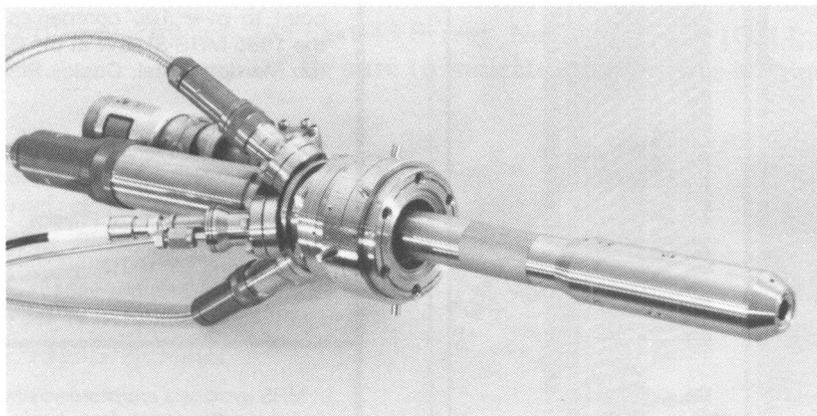
To submit a paper or register to attend, contact either Joseph A. Pask or Anthony G. Evans, Department of Materials Science and Materials Engineering, University of California, Berkeley, California 94720.



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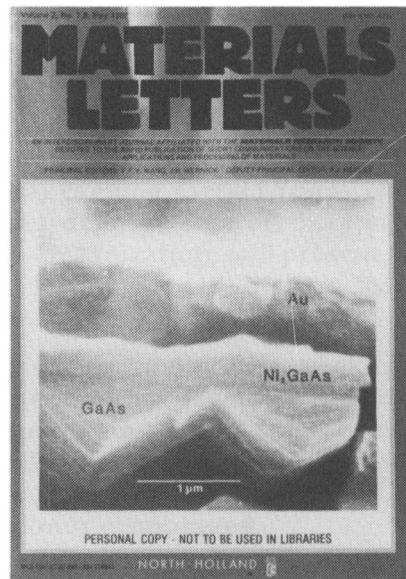
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